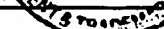


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				Application Number	10/760,025
				Filing Date	January 16, 2004
				First Named Inventor	Khalil Najafi, et al.
				Group Art Unit	
				Examiner Name	
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## U.S. PATENT DOCUMENTS

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## FOREIGN PATENT DOCUMENTS

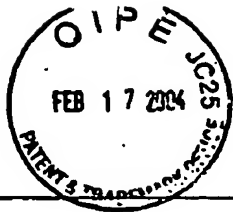
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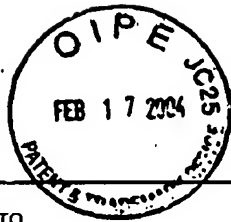


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		First Named Inventor	Khalil Najafi, et al.		
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Sheet	2	of	4	Attorney Docket Number	UOM 0289 PUSP
<b>OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS</b>					
Examiner Initials <sup>*</sup>	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.			T <sup>2</sup>
KZ		YAZDI, NAVID, ET AL., Micromachined Inertial Sensors, Proceedings of the IEEE, Vol. 86, No. 8, August 1998, pps. 1640-1659			
KZ		YAZDI, NAVID, Micro-g Silicon Accelerometers with High Performance CMOS Interface Circuitry, EECS, 1999, The University of Michigan, Ann Arbor, Michigan			
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KZ		LU, C., ET AL., A Monolithic Surface Micromachined Accelerometer with Digital Output, IEEE Journal of Solid-State Circuits, Vol. 30, No. 12, December 1995, pps. 1367-1373			
KZ		BOSER, BERNHARD E., ET AL., Surface Micromachined Accelerometers, IEEE Journal of Solid-State Circuits, Vol. 31, No. 3, March 3, 1996, pps. 366-375			
KZ		CROSS-BOW, High Sensitivity Accelerometer, LF Series Data Sheet, San Jose, California, 2001			
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KZ		WU, JIANGFENG, ET AL., A Low-Noise Low-Offset Chopper-Stabilized Capacitive-Readout Amplifier for CMOS MEMS Accelerometers, IEEE International Solid State Circuits Conference ISSCC 2002, San Francisco, California			
KZ		LEMKIN, M., ET AL., A Low-Noise Digital Accelerometer Using Integrated SOI-MEMS Technology, 10 <sup>th</sup> International Conference Solid-State Sensors And Actuators, Transducers 1999, Sendai, Japan			
KZ		ISHIHARA, KEI, ET AL., An Inertial Sensor Technology Using DRIE and Wafer Bonding with Interconnecting Capability, Journal of Microelectromechanical Systems, Vol. 8, No. 4, December 1999, pps. 403-408			

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Sheet	3	of	4	Attorney Docket Number	UOM 0289 PUSP

**OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS**

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KZ		GRIFFIN, W.S., ET AL., A Study of Fluid Squeeze-Film Damping, ASME Journal of Basic Engineering, June 1996, pps. 451-456	
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KZ		CHAE, JUNSEOK, ET AL., A Hybrid Silicon-On-Glass (SOG) Lateral Micro-Accelerometer With CMOS Readout Circuitry, 15 <sup>th</sup> IEEE International Conference on Micro Electro Mechanical Systems, MEMS 2002, Las Vegas, Nevada,	
KZ		YAZDI, NAVID, ET AL., An All-Silicon Single-Wafer Fabrication Technology For Precision Microaccelerometers, 9 <sup>th</sup> International Conference Solid-State Sensors and Actuators, Transducers 1997, Chicago, IL, pps. 1181-1184	
KZ		DOSCHER, JAMES, ADXL105: a Lower Noise, Wider Bandwidth Accelerometer Rivals Performance of More Expensive Sensors, 1999 Analog Dialogue 33-6, 1999 Analog Devices	

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HR		HONEYWELL, ASA7000, Micromachined Accelerometer, Data Sheet, July 2001  MOTOROLA, MMA2201D, Surface Mount Micromachined Accelerometer, Data Sheet 2000, pps. 1-8			
HR		ROYLANCE, L.M., ET AL., A Batch Fabricated Silicon Accelerometer, IEEE Trans Electron Devices, Vol. ED-26, No. 12, December 1979, pps. 1911-1917			
HR		SALIAN, A., ET AL., A High-Performance Hybrid CMOS Microaccelerometer, Solid-State Sensors and Actuators Workshop, Hilton Head Island, SC, June 4-8, 2000, pps. 285-288			
HR		ROARK, R.J., ET AL., Roark's Formulas for Stress and Strain, 6 <sup>th</sup> Ed. 1989, New York: McGraw-Hill, xiv, Vol. 763			
HR		WARREN, KEITH, Navigation Grade Silicon Accelerometers with Sarificially Etched SIMOX and BESOI Structure, Solid-State Sensors and Actuators Workshop, June 13-16, 1994 Hilton Head Island, SC, pps. 69-72			
HR		ENDEVCO, Variable Capacitance Accelerometer, Model 7596, Data Sheet, 2000			
HR		CHAE, JUNSEOK, ET AL., A Monolithic Three-Axis Silicon Capacitive Accelerometer With Micro-G Resolution, 12 <sup>th</sup> IEEE International Conference on Solid-State Sensors, Actuators and Microsystems, Transducers 2003, Boston, MA			

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<b>Filing Date</b>	January 16, 2004
<b>First Named Inventor</b>	Khalil Najafi, et al.
<b>Group Art Unit</b>	2858
<b>Examiner Name</b>	

Sheet 1	of 1	Attorney Docket Number	UOM 0289 PUSP
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